



DEPARTMENT OF ELECTRONIC ENGINEERING and IEEE LEOS Jointly
Present a Seminar on

Nanoimprinting Technology And Micro Gas Chromatography

By

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Abstract

New development in nanoimprinting technology will be reviewed. These include reversal imprinting, imprinting on flexible substrates, forming three-dimensional microstructures, generating nanofluidic channels, and inking at low temperature and pressure. In addition, a microfabricated gas chromatography system with micromachined preconcentrator, column, and chemical sensor will be presented. Such microsystem has the advantages of having higher sensitivity, smaller size, and lower power consumption.

Brief Biography

Stella W. Pang received her Sc.B. degree from Brown University in Electrical Engineering and Computer Science in 1977 and M.Sc. and Ph.D. degrees in Electrical Engineering and Computer Science from Princeton University in 1978 and 1981. From 1981 to 1989, Dr. Pang was with Lincoln Laboratory at the Massachusetts Institute of Technology. She joined the University of Michigan in 1990. Currently, she is a professor in electrical engineering and computer science and the associate dean for graduate education in the college of engineering. Dr. Pang's research interests include nanofabrication technology for microelectromechanical, microelectronic and optical devices. She has over 300 technical papers, book chapters and presentations and is the editor and author of 16 books, journals and conference proceedings. She has taught over 18 short courses on microfabrication technology for microelectronic manufacturing and microelectromechanical systems. She is a Fellow of IEEE, ECS and AVS.

Date : August 7, 2003 (Thursday)
Time : 4.00 p.m. - 5.00 p.m.
Venue : G6302 (Green Zone)

ALL ARE WELCOME

For enquiry please call Prof. Edwin Y.B. Pun at 2788-8609